

SISPAD 2026 Workshop

Back to Fundamentals: Semiconductor Process and Transport Simulation

Sunday, September 27, 2026 | 9:30 - 17:10 | Hall, 6F, Kumamoto City International Center

A guide to the building, and two things to know before you go in, are on the next page of this PDF.

9:30 - 9:40

Welcome Remark

Hiroki Tokuhira (Kioxia)

Part A: Process Simulation

Organizers: H. Tokuhira (Kioxia), K. Uchida (Univ. of Tokyo)

9:40 - 10:20

Mark J. Kushner (University of Michigan)

Overview of Integrated Plasma Reactor and Feature Scale Modeling: Algorithms and Applications to Cryogenic Etching

10:20 - 11:00

Yoshihiro Kangawa (Kyushu University)

Optimal Design of MOCVD Process for AlGaIn/AlN Deep-Ultraviolet Laser Diodes: Ab Initio-Based Approach

11:00 - 11:20

Break

Coffee is served in the lobby on 6F.

11:20 - 12:00

Lado Filipovic (Vienna University of Technology)

Process Topography TCAD for Advanced Manufacturing

12:00 - 12:40

Yury Shustrov (STR Software)

Multiscale Modeling of SiGe-based Device Processing

12:40 - 14:00

Lunch (Ohiroma A + B, 5F)

A boxed lunch is provided. The room is a tatami room: please take off your shoes at the door.

Part B: Transport Simulation

Organizers: M. Shin (KAIST), Y.-S. Kim (Samsung)

14:00 - 14:40

Marco Pala (University of Udine)

Ab initio Transport in 2D Materials Heterojunction Devices

14:40 - 15:20

Hong-Hyun Park (Samsung Semiconductor Inc.)

Simulation Development for Advanced Logic Technology at an IDM Company: Models and Tools Built to Support Real Device Issues

15:20 - 15:40

Break

Coffee is served in the lobby on 6F.

15:40 - 16:20

Christoph Jungemann (RWTH Aachen University)

Semiclassical Modeling of Electron Transport in Semiconductor Devices based on the Boltzmann Equation

16:20 - 17:00

Junichiro Shiomi (University of Tokyo)

Multiscale Phonon Transport Modeling and Semiconductor Thermal Management

17:00 - 17:10

Closing Remark

Mincheol Shin (KAIST)

Workshop Venue Guide

Kumamoto City International Center | 4-18 Hanabata-cho, Chuo-ku, Kumamoto 860-0806, Japan

One building, one bank of elevators. Everything you need on September 27 is on three floors.

7F	Upper level of the Hall. No sessions on 7F.	
6F	1 Hall All workshop sessions, 9:30 - 17:10. The Hall is a two-storey room open to 7F.	2 Lobby Workshop registration desk, from 8:30. Coffee is served here during both breaks.
5F	3 Ohiroma A + B Lunch, 12:40 - 14:00. A tatami room: shoes must be taken off at the door. Plastic bags for your shoes are handed out there.	
2F - 4F	Meeting rooms of the Center. Not used by SISPAD 2026.	
1F	4 Main Entrance Elevators to every floor are just inside the entrance. The Center's own reception desk and a cafe are also on 1F.	

Please note

- No food or drink is allowed in the Hall on 6F. This includes water. Please finish your drink in the lobby before going in.
- The lunch room on 5F is a tatami room and shoes must be taken off. Plastic bags for your shoes are handed out at the door.
- Pick up your congress bag at the registration desk in the lobby on 6F.
- The main conference on September 28 - 30 is at Kumamoto-Jo Hall, a different building. A floor map of that venue is on the second page of the Schedule at a Glance on the conference website.

Getting here

Tram	Hanabata-cho stop on the Kumamoto City Tram, then about 2 minutes on foot. About 15 minutes from JR Kumamoto Station.
Bus	Sakuramachi Bus Terminal, then about 3 minutes on foot.
Aso Kumamoto Airport	Direct bus to Sakuramachi Bus Terminal, about 46 minutes, then about 3 minutes on foot.
Fukuoka Airport	Subway to Hakata Station (about 10 minutes), Kyushu Shinkansen to JR Kumamoto Station (about 38 minutes), then the city tram (about 12 minutes).
Kumamoto-Jo Hall	The main conference venue is part of the Sakuramachi complex, about 5 minutes on foot from here.